

United States Patent and Trademark Office

UNITED STATES DEPARTMENT OF COMMERCE United States Patent and Trademark Office Address: COMMISSIONER OF PATENTS AND TRADEMARKS Washington, D.C. 20221 www.uspio.gov

	<u> </u>			
APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
09/993,890	11/27/2001	Satoru Yamagata	925-219	7689
75	90 03/12/2003			
NIXON & VANDERHYE P.C.			EXAMINER	
1100 North Glebe Road, 8th Floor Arlington, VA 22201		LI	LEE, CA	E, CALVIN
			ART UNIT	PAPER NUMBER
			2825	
			DATE MAILED: 03/12/2003	

Please find below and/or attached an Office communication concerning this application or proceeding.

		Application No.	Applicant(s)			
		09/993,890	YAMAGATA ET AL.			
Office Action Summary		Examiner	Art Unit			
		Lee Calvin	2825			
	The MAILING DATE of this communication a	appears on the cover she	et with the correspondenc address			
Period for	Reply	DIVIO CET TO EVDIDE	3 MONTH(S) FROM			
THE M - Extens after S - If the p - If NO p - Failure	RTENED STATUTORY PERIOD FOR REPAIRING DATE OF THIS COMMUNICATION Signs of time may be available under the provisions of 37 CFR (X) (6) MONTHS from the mailing date of this communication. Deriod for reply specified above is less than thirty (30) days, a period for reply is specified above, the maximum statutory period to reply within the set or extended period for reply will, by state of the period by the Office later than three months after the maximum adjustment. See 37 CFR 1.704(b).	N. 1.136(a). In no event, however, noted that it is not event, however, noted to be statutory minimum and will expire SIX (6) that is not expire SIX (6) that is not expire SIX (6) that is not expected to be statuted	of thirty (30) days will be considered timely. S) MONTHS from the mailing date of this communication. Some ABANDONED (35 U.S.C. § 133).			
1)	Responsive to communication(s) filed on _	·				
2a) □	This action is FINAL . 2b)	This action is non-final.				
3)	The state of the merits is a condition for allowance except for formal matters, prosecution as to the merits is					
•	on of Claims					
4) 🖾	Claim(s) 1-4 is/are pending in the applicati	ion.	, m			
	4a) Of the above claim(s) is/are with	drawn from consideration	Π.			
5) 🗌	Claim(s) is/are allowed.					
6)⊠	Claim(s) 3-4 is/are rejected.					
7)	Claim(s) 2 is/are objected to.		1			
	Claim(s) are subject to restriction ar	nd/or election requireme	ML.			
, • ·	on Papers					
9) 🗌 🤄	The specification is objected to by the Exam	niner.	o by the Examiner.			
10) 🔲	The drawing(s) filed on is/are: a)□ a	accepted or b) objected t	abevance See 37 CFR 1.85(a).			
	Applicant may not request that any objection	is: a)[] approved	h) disapproved by the Examiner.			
11) 🗌	The proposed drawing correction filed on _	in raphy to this Office action				
	If approved, corrected drawings are required					
	The oath or declaration is objected to by the	C LAGITITION.				
Priority	under 35 U.S.C. §§ 119 and 120	noign priority under 25 H	S C & 119(a)-(d) or (f).			
	Acknowledgment is made of a claim for fo	reign priority under 35 0				
(a)		ti kara baas saabu	ad			
	1.☑ Certified copies of the priority documents have been received. 2.☐ Certified copies of the priority documents have been received in Application No					
	2. Certified copies of the priority docur	ments have been receive	boon received in this National Stage			
	3. Copies of the certified copies of the application from the Internation See the attached detailed Office action for	al bulgau (FOT IVaio 17	- L (u)).			
	See the attached detailed of a claim for dor	mestic priority under 35	U.S.C. § 119(e) (to a provisional application).			
	The translation of the foreign language	re provisional application	has been received.			
15)	Acknowledgment is made of a claim for do	mestic priority under 35	U.S.C. §§ 120 and/or 121.			
Attachme		∆\ \ \ \ \ \ \ \ \ \ \ \ \ \ \ \ \ \ \	nterview Summary (PTO-413) Paper No(s)			
2) Not	ice of References Cited (PTO-892) ice of Draftsperson's Patent Drawing Review (PTO-94 ormation Disclosure Statement(s) (PTO-1449) Paper N	18) 5) 🔲 N	lotice of Informal Patent Application (PTO-152) ther:			

Application No: 09/993,890

Docket No: 925-219

Page 2 YAMAGATA et al.

OFFICE ACTION

Specification

1. The specification is objected to because of the following informality:

Page 1, line 15, replace "10B" with --10C--

Page 2, line 24, before "a source/drain region" delete --the--

Page 18, line 15, replace "Fig. 6A" with --Fig. 6--

Page 18, line 20, replace "films 10, 2." with --films 10 and 11--

Claim Objection

2. Claim 1 is objected to because of the following informality:

Claim 1, lines 1-5, replace "a nonvolatile semiconductor memory wherein memory cells each having a tunnel oxide film, a floating gate, a first insulating film and a control gate stacked in this order are formed in a matrix on a semiconductor substrate" with --nonvolatile semiconductor memory cells formed in a matrix on a semiconductor substrate, wherein each memory cell has a tunnel oxide film, a floating gate, a first insulating film, and a control gate stacked in this order--

Claim Rejections - 35 U.S.C. § 102

3. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless –

(b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.

4. Claim 1 is rejected under 35 U.S.C. 102(b) as being anticipated by Chen et al. (US 5,482,881).

Chen discloses a method for forming a nonvolatile memory cell, comprising of:

- forming a tunnel oxide film 120, then a first conductive layer 122 as a floating gate on a substrate
- forming a source/drain region 130 on the substrate by using the first conductive layer as a mask
- forming a first insulating film 124, then a second conductive layer 126 as a control gate on the first conductive layer [Figs. 4D, 5 and cols. 2, 7-8]
- etching a portion of the tunnel oxide film immediately below a sidewall of the floating gate
- forming a second insulating film 720 over the structure [Fig. 6F]

Application No: 09/993,890

Docket No: 925-219

YAMAGATA et al.

Since Chen teaches nonvolatile memory cells array [Fig. 2] arranged in a matrix on a substrate 116, wherein each memory cell has a cross section in a (1-1) direction shown on Fig. 3, Chen inherently teaches that the first and second conductive layers are patterned in stripes extending in either one of the two directions

Claim Rejections - 35 U.S.C. § 103

- 5. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
 - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.
- 6. Claims 3 and 4 are rejected under 35 U.S.C. 103(a) as being unpatentable over Chen et al. (US 5,482,881) in view of Hong et al. (US 5,445,984).

Chen fails to teach that the tunnel oxide is isotropically etched using a fluorinated acid and the second insulating film is formed by CVD. Hong teaches or suggests that a insulating layer is formed by CVD [col. 5] and a tunnel oxide 22 is etched by means of HF in wet etch [col. 7].

It would have been obvious to one having ordinary skill in the art to have modified the fabricating method of *Chen* by utilizing CVD process to form an insulating film and wet etch to etch a tunnel oxide because those processes/techniques are notoriously well known in the art either to form an insulating film economically or to etch a tunnel oxide effectively in EPROM formation

Allowable Subject Matter

7. Claim 2 is objected to as being dependent upon a rejected base claim, but would be allowable if rewritten in independent form including all of the limitations of the independent claim because none of the cited references teaches thermally oxidizing the floating gate sidewall.

Any inquiry concerning this communication from the Examiner should be directed to *Calvin Lee* at (703) 306-5854 from 7:00 to 17:00 (Monday-Thursday). If attempts to reach the examiner by telephone are unsuccessful, Art Unit 2825's Supervisory Patent Examiner *Matthew Smith* can be reached at (703) 308-1323.

Any inquiry relating to the status of this application should be directed to the Group receptionist whose telephone number is (703) 308-0596. The fax phones are (703) 872-9318 for regular communications and (703) 872-9319 for After-Final communications.

February **29**, 2003

MATTHEW SMITH SUPERVISORY PATENT EXAMINER TECHNOLOGY CENTER 2800